

The listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1.-15. (Canceled)

16. (Currently Amended) A method of fabricating a light-emitting device, comprising:

forming an element substrate having an electrode connected to a semiconductor element;

inspecting the element substrate; and

forming [[the]] an EL layer in contact with the electrode connected to the semiconductor element;

wherein the element substrate is inspected by:

emitting electromagnetic waves from a source of electromagnetic waves;

ionizing a gas between the element substrate and [[the]] an opposing detector substrate;

measuring a current between the element substrate and the opposing detector substrate; and

inspecting the current-flowing state of a pixel electrode of the element substrate.

17. (Original) A method according to claim 16, wherein the source of electromagnetic waves generates electromagnetic waves or X-rays of a wavelength of 0.01 to 100 nm.

18. (Canceled)

19. (Previously Presented) A method according to claim 16 wherein said light-emitting device is incorporated into one selected from the group consisting of a video camera, a head mounted type electrical appliance, an image playback device, a head mounted display, a personal computer, a portable telephone, an audio reproducing device, and a digital camera.

20. (Canceled)

21. (Previously Presented) A method according to claim 16 wherein the opposing detector substrate comprises an opposing detector electrode comprising a material selected from the group consisting of beryllium and aluminum.

22. (Previously Presented) A method according to claim 16 wherein the opposing detector substrate comprises an opposing detector electrode formed in a stripe.

23. (Previously Presented) A method according to claim 16 wherein the opposing detector substrate comprises an opposing detector electrode formed in a mesh.

24. (Previously Presented) A method according to claim 16 wherein the opposing detector substrate comprises a material selected from the group consisting of a glass, a quartz, a vinyl chloride and acrylic resin.

25. (Previously Presented) A method according to claim 16 wherein the opposing detector substrate comprises an organic resin.

26. (Previously Presented) A method according to claim 16 further comprising:

forming a cathode over the EL layer.

27. (Previously Presented) A method according to claim 26 wherein the EL layer comprises an organic material.

28. (Currently Amended) A method of fabricating a light-emitting device, comprising:

forming an element substrate having an electrode connected to a semiconductor element;

inspecting the element substrate while moving the element substrate; and

forming ~~[[the]]~~ an EL layer in contact with the electrode connected to the semiconductor element;

wherein the element substrate is inspected by:

emitting electromagnetic waves from a source of electromagnetic waves;

ionizing a gas between the element substrate and an opposing detector substrate;

measuring a current between the element substrate and the opposing detector substrate; and

inspecting the current-flowing state of a pixel electrode of the element substrate.

29. (Previously Presented) A method according to claim 28, wherein the source of the electromagnetic waves generates electromagnetic waves or X-rays of a wavelength of 0.01 to 100 nm.

30. (Previously Presented) A method according to claim 28 wherein said light-emitting device is incorporated into one selected from the group consisting of a video camera, a head mounted type electrical appliance, an image playback device, a head

mounted display, a personal computer, a portable telephone, an audio reproducing device, and a digital camera.

31. (Canceled)

32. (Previously Presented) A method according to claim 28 wherein the opposing detector substrate comprises an opposing detector electrode comprising a material selected from the group consisting of beryllium and aluminum.

33. (Previously Presented) A method according to claim 28 wherein the opposing detector substrate comprises an opposing detector electrode formed in a stripe.

34. (Previously Presented) A method according to claim 28 wherein the opposing detector substrate comprises an opposing detector electrode formed in a mesh.

35. (Previously Presented) A method according to claim 28 wherein the opposing detector substrate comprises a material selected from the group consisting of a glass, a quartz, a vinyl chloride and acrylic resin.

36. (Previously Presented) A method according to claim 28 wherein the opposing detector substrate comprises an organic resin.

37. (Previously Presented) A method according to claim 28 further comprising:
forming a cathode over the EL layer.

38. (Previously Presented) A method according to claim 37 wherein the EL layer comprises an organic material.
